

SEMICONDUCTOR DEVICE TESTING APPARATUS AND A TEST TRAY FOR USE IN THE TESTING APPARATUS

ABSTRACT

An IC tester which is capable of reducing the time required before
5 completion of testing on all of ICs to be tested is provided. The depth (length
in the Y-axis direction) of the constant temperature chamber 4 and the exit
chamber 5 is expanded by a dimension corresponding approximately to one
transverse width (length of the minor edge) of the rectangular test tray 3, and
two generally parallel test tray transport paths or alternatively a widened test
10 tray transport path broad enough to transport two test trays simultaneously
with the two test trays juxtaposed in a direction transverse to the widened test
tray transport path are provided in the section of test tray transport path
extending from the soak chamber 41 in the constant temperature chamber 4
through the testing section 42 in the constant temperature chamber 4 to the
15 exit chamber 5 so that two test trays may be simultaneously transported along
the two test tray transport paths or the widened test tray transport path.